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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

: Confirmation No. 2322

Yoichiro YASHIRO et al.

: Attorney Docket No. 2003\_1205A

Serial No. 10/647,479

: Group Art Unit 1762

Filed August 26, 2003

: Examiner Cachet I. Sellman

PLASMA PROCESSING METHOD  
AND APPARATUS

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**RESPONSE**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In response to the Restriction Requirement of June 6, 2006, Applicants hereby elect Group II, which is drawn to an apparatus and is embodied by claims 12-17.

Having made the required election, a full examination on the merits of the elected group is requested.

THE COMMISSIONER IS AUTHORIZED  
TO CHARGE ANY DEFICIENCY IN THE  
FEES FOR THIS PAPER TO DEPOSIT  
ACCOUNT NO. 23-0975

Respectfully submitted,

Yoichiro YASHIRO et al.

By:

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